

WHAT IS CLAIMED IS:

1. A magnetic head actuator comprising:
a head-holding substrate having a pair of movable arms
5 for holding a magnetic head; and
piezoelectric elements fixed along the pair of movable
arms to move the pair of movable arms in response to an
applied voltage,
wherein the head-holding substrate comprises a fired
10 glass-ceramic compact and all surfaces of the substrate are
fired.
2. A magnetic head actuator according to Claim 1,
wherein the fired glass-ceramic compact comprises at least
15 one of SiO_2 , B_2O_3 , and Al_2O_3 .
3. A magnetic head actuator according to Claim 2,
wherein the fired glass-ceramic compact has a mechanical
strength of 200 MPa or more.
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4. A magnetic head actuator according to Claim 3,
wherein the fired glass-ceramic compact has a glass
component comprising PbO , B_2O_3 , SiO_2 , CaO , and a ceramic
component comprising Al_2O_3 .
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5. A magnetic head actuator according to Claim 3,
wherein the fired glass-ceramic compact has a glass
component comprising MgO , Al_2O_3 , SiO_2 , B_2O_3 , and a ceramic

component comprising SiO₂.

6. A magnetic head actuator according to Claim 3,
wherein the fired glass-ceramic compact has a glass
5 component comprising B₂O₃, SiO₂, and a ceramic component
comprising Al₂O₃.

7. A magnetic head actuator according to Claim 3,
wherein the fired glass-ceramic compact comprises CaO, Al₂O₃,
10 and SiO₂.

8. A magnetic head actuator according to Claim 3,
wherein the fired glass-ceramic compact has a glass
component comprising Li₂O, SiO₂, MgO, Al₂O₃, and a ceramic
15 component comprising SiO₂ and Al₂O₃.

9. A magnetic head actuator according to Claim 1,
wherein the piezoelectric elements are formed on the head-
holding substrate by printing and are fired at a lower
20 temperature than the sintering temperature of the fired
glass-ceramic compact.

10. A magnetic head actuator according to Claim 9,
wherein the piezoelectric elements comprise PZT.

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11. A method for manufacturing a magnetic head actuator,
comprising:
preparing a glass-ceramic green sheet;

processing the glass-ceramic green sheet into a desired shape;

firing the glass-ceramic green sheet by non-shrinkage firing to provide a fired glass-ceramic sheet for head-holding substrates, all surfaces of the fired glass-ceramic sheet being fired;

forming a pair of piezoelectric elements on each head-holding substrate by printing with a piezoelectric material having a lower sintering temperature than that of the fired glass-ceramic sheet; and

firing the pair of piezoelectric elements at a lower temperature than the sintering temperature of the fired glass-ceramic sheet.

15 12. A method for manufacturing a magnetic head actuator according to Claim 11, wherein the glass-ceramic green sheet comprises a glass-ceramic material powder containing at least one of SiO_2 , B_2O_3 , and Al_2O_3 .

20 13. A method for manufacturing a magnetic head actuator according to Claim 12, wherein the fired glass-ceramic sheet has a mechanical strength of 200 MPa or more.

25 14. A method for manufacturing a magnetic head actuator according to Claim 13, wherein the fired glass-ceramic sheet has a glass component comprising PbO , B_2O_3 , SiO_2 , CaO , and a ceramic component comprising Al_2O_3 .

15. A method for manufacturing a magnetic head actuator according to Claim 13, wherein the fired glass-ceramic sheet has a glass component comprising MgO, Al₂O₃, SiO₂, B₂O₃, and a ceramic component comprising SiO₂.

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16. A method for manufacturing a magnetic head actuator according to Claim 13, wherein the fired glass-ceramic sheet has a glass component comprising B₂O₃, SiO₂, and a ceramic component comprising Al₂O₃.

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17. A method for manufacturing a magnetic head actuator according to Claim 13, wherein the fired glass-ceramic sheet comprises CaO, Al₂O₃, and SiO₂.

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18. A method for manufacturing a magnetic head actuator according to Claim 13, wherein the fired glass-ceramic sheet has a glass component comprising Li₂O, SiO₂, MgO, Al₂O₃, SiO₂, and a ceramic component comprising Al₂O₃.

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19. A method for manufacturing a magnetic head actuator according to Claim 11, wherein the pair of piezoelectric elements comprise PZT.

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20. A method for manufacturing a magnetic head actuator according to Claim 11, wherein, in the step of processing the glass-ceramic green sheet into a desired shape, openings are formed in the glass-ceramic green sheet by laser processing to define the shape of the head-holding

substrates.

21. A method for manufacturing a magnetic head actuator according to Claim 11, wherein, in the step of processing 5 the glass-ceramic green sheet into a desired shape, openings are formed in the glass-ceramic green sheet by pressing to define the shape of the head-holding substrates.

22. A method for manufacturing a magnetic head actuator 10 according to Claim 20, wherein the openings define a stationary portion of each head-holding substrate, and a pair of movable arms that extend from both ends of each stationary portion to hold a magnetic head at free ends of the pair of movable arms.

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23. A method for manufacturing a magnetic head actuator according to Claim 21, wherein the openings define a stationary portion of each head-holding substrate, and a pair of movable arms that extend from both ends of each 20 stationary portion to hold a magnetic head at free ends of the pair of movable arms.

24. A method for manufacturing a magnetic head actuator according to Claim 11, wherein multiple head-holding 25 substrates are defined in the fired glass-ceramic sheet at the same time and, before the step of firing the pair of piezoelectric elements, the fired glass-ceramic sheet is cut to separate the head-holding substrates.

25. A hard disk drive, comprising:
a magnetic disk rotatable about a central axis by a
motor;
- 5 a coarse adjustment shaft supporting the base of a swing
arm, pivotable about the coarse adjustment shaft;
 a swing arm actuator operatively connected to the swing
arm;
 a magnetic head actuator disposed at an end of the swing
10 arm distal from the coarse adjustment shaft;
 the magnetic head actuator having a head-holding
substrate having a pair of movable arms for holding a
magnetic head; and
 piezoelectric elements fixed along the pair of movable
15 arms to move the pair of movable arms in response to an
applied voltage,
 wherein the head-holding substrate comprises a fired
glass-ceramic compact and all surfaces of the substrate are
fired.
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26. An apparatus for accurately positioning a magnetic
head, comprising:
 a magnetic head-holding structure;
 a coarse adjustment mechanism that positions the
25 magnetic head with respect to a magnetic medium; and
 a fine adjustment mechanism being actuated by a
piezoelectric element incorporated in the magnetic head-
holding structure,

wherein the fine adjustment mechanism comprises a fired glass-ceramic compact and all surfaces of the substrate are fired.

5 27. A means for accurately positioning a magnetic head with respect to a recording medium, comprising:

means for holding the magnetic head;

means for coarsely adjusting the magnetic head position;

and

10 means for finely adjusting the magnetic head position.

28. A means for increasing the spatial density of magnetic data recording and reproduction, comprising:

means for recording and reproducing data;

15 means for accurately positioning a magnetic head with respect to a recording medium.

29. A method of increasing the spatial density of magnetic data recording and reproduction, comprising:

20 providing a rotating magnetic disk; and

providing a coarse positioning mechanism that holds a fine positioning mechanism and provides coarse positioning of the magnetic head with respect to the magnetic disk;

25 wherein the fine positioning mechanism holds a magnetic head and is attached to the coarse positioning mechanism, the fine positioning mechanism having a head-holding substrate comprising a fired glass-ceramic compact and all surfaces of the substrate are fired, and

wherein the fine positioning mechanism has piezoelectric elements to alter the position of the magnetic head in response to an applied voltage.